

Takaaki Aoki

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The third column is the impact factor (IF) of the journal, and the fourth column is the number of citations of the article.

156 papers	2,156 citations	25 h-index	40 g-index
174 ext. papers	2,266 ext. citations	2.2 avg, IF	4.46 L-index

#	Paper	IF	Citations
156	Precise and fast secondary ion mass spectrometry depth profiling of polymer materials with large Ar cluster ion beams. <i>Rapid Communications in Mass Spectrometry</i> , 2009 , 23, 1601-6	2.2	174
155	Measurements of secondary ions emitted from organic compounds bombarded with large gas cluster ions. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2007 , 256, 493-496	1.2	140
154	Molecular depth profiling of multilayer structures of organic semiconductor materials by secondary ion mass spectrometry with large argon cluster ion beams. <i>Rapid Communications in Mass Spectrometry</i> , 2009 , 23, 3264-8	2.2	86
153	Molecular dynamics simulation of damage formation by cluster ion impact. <i>Nuclear Instruments & Methods in Physics Research B</i> , 1997 , 121, 49-52	1.2	73
152	Nano-processing with gas cluster ion beams. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2000 , 164-165, 944-959	1.2	73
151	Non-linear processes in the gas cluster ion beam modification of solid surfaces. <i>Materials Science & Engineering A: Structural Materials: Properties, Microstructure and Processing</i> , 1998 , 253, 249-257	5.3	59
150	STM observation of HOPG surfaces irradiated with Ar cluster ions. <i>Nuclear Instruments & Methods in Physics Research B</i> , 1997 , 121, 498-502	1.2	58
149	A new secondary ion mass spectrometry (SIMS) system with high-intensity cluster ion source. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2004 , 219-220, 463-467	1.2	55
148	A fragment-free ionization technique for organic mass spectrometry with large Ar cluster ions. <i>Applied Surface Science</i> , 2008 , 255, 1588-1590	6.7	54
147	High sputtering yields of organic compounds by large gas cluster ions. <i>Applied Surface Science</i> , 2008 , 255, 1148-1150	6.7	51
146	Molecular dynamics study of damage formation characteristics by large cluster ion impacts. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2003 , 202, 278-282	1.2	49
145	Matrix-free high-resolution imaging mass spectrometry with high-energy ion projectiles. <i>Journal of Mass Spectrometry</i> , 2009 , 44, 128-36	2.2	44
144	Angular distributions of the particles sputtered with Ar cluster ions. <i>Materials Chemistry and Physics</i> , 1998 , 54, 262-265	4.4	42
143	What size of cluster is most appropriate for SIMS?. <i>Applied Surface Science</i> , 2008 , 255, 1235-1238	6.7	41
142	Progress and applications of cluster ion beam technology. <i>Current Opinion in Solid State and Materials Science</i> , 2015 , 19, 12-18	12	38
141	Secondary ion mass spectrometry with gas cluster ion beams. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2002 , 190, 860-864	1.2	37
140	Molecular dynamics simulations for gas cluster ion beam processes. <i>Vacuum</i> , 2010 , 84, 994-998	3.7	35

¹³⁹	Cluster size dependence of the impact process on a carbon substrate. <i>Nuclear Instruments & Methods in Physics Research B</i> , 1999 , 153, 264-269	1.2	35
¹³⁸	Reduction of boron transient enhanced diffusion in silicon by low-energy cluster ion implantation. <i>Materials Chemistry and Physics</i> , 1998 , 54, 80-83	4.4	33
¹³⁷	Novel SIMS system with focused massive cluster ion source for mass imaging spectrometry with high lateral resolution. <i>Applied Physics Express</i> , 2014 , 7, 056602	2.4	32
¹³⁶	Analysis of organic semiconductor multilayers with Ar cluster secondary ion mass spectrometry. <i>Surface and Interface Analysis</i> , 2011 , 43, 95-98	1.5	32
¹³⁵	SIMS with highly excited primary beams for molecular depth profiling and imaging of organic and biological materials. <i>Surface and Interface Analysis</i> , 2010 , 42, 1612-1615	1.5	31
¹³⁴	Cluster ion bombardment on atomically flat Au(111) solid surfaces. <i>Materials Chemistry and Physics</i> , 1998 , 54, 76-79	4.4	30
¹³³	Secondary ion mass spectrometry with gas cluster ion beams. <i>Applied Surface Science</i> , 2003 , 203-204, 214-218	6.7	30
¹³²	Molecular dynamics simulations of surface modification and damage formation by gas cluster ion impacts. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2006 , 242, 517-519	1.2	27
¹³¹	Energy dependence of a single trace created by C60 ion impact. <i>Materials Chemistry and Physics</i> , 1998 , 54, 143-146	4.4	25
¹³⁰	The effect of incident cluster ion energy and size on secondary ion yields emitted from Si. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2007 , 256, 528-531	1.2	25
¹²⁹	Molecular dynamics and Monte-Carlo simulation of sputtering and mixing by ion irradiation. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2001 , 180, 312-316	1.2	24
¹²⁸	Molecular dynamics simulations of cluster impacts on solid targets: implantation, surface modification, and sputtering. <i>Journal of Computational Electronics</i> , 2014 , 13, 108-121	1.8	21
¹²⁷	Molecular dynamics simulation of a carbon cluster ion impacting on a carbon surface. <i>Materials Chemistry and Physics</i> , 1998 , 54, 139-142	4.4	21
¹²⁶	Size effect in cluster collision on solid surfaces. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2007 , 257, 627-631	1.2	21
¹²⁵	Molecular dynamics simulations of sequential cluster ion impacts. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2005 , 228, 46-50	1.2	20
¹²⁴	The effect of incident energy on molecular depth profiling of polymers with large Ar cluster ion beams. <i>Surface and Interface Analysis</i> , 2011 , 43, 221-224	1.5	19
¹²³	Highly sensitive molecular detection with swift heavy ions. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2011 , 269, 2251-2253	1.2	18
¹²²	Yield enhancement of molecular ions with MeV ion-induced electronic excitation. <i>Applied Surface Science</i> , 2008 , 255, 1591-1594	6.7	18

121	MeV-energy probe SIMS imaging of major components in animal cells etched using large gas cluster ions. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2010 , 268, 1736-1740	1.2	17
120	Peptide dissociation patterns in secondary ion mass spectrometry under large argon cluster ion bombardment. <i>Rapid Communications in Mass Spectrometry</i> , 2013 , 27, 1490-6	2.2	16
119	Surface morphology of PMMA surfaces bombarded with size-selected gas cluster ion beams. <i>Surface and Interface Analysis</i> , 2011 , 43, 120-122	1.5	16
118	Molecular dynamics study of glancing angle gas cluster irradiation on irregular-structured surfaces. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2007 , 261, 639-642	1.2	16
117	Surface structure dependence of impact processes of gas cluster ions. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2004 , 216, 185-190	1.2	16
116	Development of gas cluster ion beam irradiation system with an orthogonal acceleration TOF instrument. <i>Surface and Interface Analysis</i> , 2013 , 45, 522-524	1.5	15
115	Molecular dynamics simulations of surface smoothing and sputtering process with glancing-angle gas cluster ion beams. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2007 , 257, 645-648	1.2	14
114	STM observation of surface vacancies created by ion impact. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2000 , 164-165, 650-655	1.2	14
113	Defect characteristics by boron cluster ion implantation. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2003 , 206, 855-860	1.2	13
112	Study on the detection limits of a new argon gas cluster ion beam secondary ion mass spectrometry apparatus using lipid compound samples. <i>Rapid Communications in Mass Spectrometry</i> , 2014 , 28, 917-20	2.2	12
111	Evaluation of Damage Layer in an Organic Film with Irradiation of Energetic Ion Beams. <i>Japanese Journal of Applied Physics</i> , 2010 , 49, 036503	1.4	12
110	Imaging mass spectrometry with nuclear microprobes for biological applications. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2009 , 267, 2144-2148	1.2	12
109	Molecular dynamics study of surface modification with a glancing angle gas cluster ion beam. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2007 , 255, 265-268	1.2	12
108	Cluster species and cluster size dependence of damage formation by cluster ion impact. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2003 , 206, 861-865	1.2	12
107	Range and Damage Distribution in Cluster Ion Implantation. <i>Materials Research Society Symposia Proceedings</i> , 1996 , 438, 363		12
106	Study of density effect of large gas cluster impact by molecular dynamics simulations. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2009 , 267, 2999-3001	1.2	11
105	MD simulation study of the sputtering process by high-energy gas cluster impact. <i>Applied Surface Science</i> , 2008 , 255, 944-947	6.7	11
104	The emission process of secondary ions from solids bombarded with large gas cluster ions. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2009 , 267, 2601-2604	1.2	10

103	Study of crater formation and sputtering process with large gas cluster impact by molecular dynamics simulations. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2009 , 267, 1424-1427	1.2	10
102	Anisotropic Etching Using Reactive Cluster Beams. <i>Applied Physics Express</i> , 2010 , 3, 126501	2.4	10
101	Molecular dynamics simulation of fluorine ion etching of silicon. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2001 , 180, 317-321	1.2	10
100	Ion-induced damage evaluation with Ar cluster ion beams. <i>Surface and Interface Analysis</i> , 2013 , 45, 167-170	1.5	9
99	Modeling of surface smoothing process by cluster ion beam irradiation. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2003 , 206, 842-845	1.2	9
98	Molecular effect on projected range in ultralow-energy ion implantation. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2003 , 211, 206-210	1.2	9
97	Cluster size effect on reactive sputtering by fluorine cluster impact using molecular dynamics simulation. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2001 , 180, 164-170	1.2	9
96	Analysis of liquid materials in low vacuum with Wet-SIMS. <i>Surface and Interface Analysis</i> , 2014 , 46, 1133-1136	1.3	8
95	Atomistic study of cluster collision on solid surfaces. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2003 , 206, 838-841	1.2	8
94	Development of ambient SIMS using mega-electron-volt-energy ion probe. <i>Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics</i> , 2016 , 34, 03H111	1.3	8
93	Prolific cluster emission in sputtering of phenylalanine by argon-cluster ion bombardment. <i>International Journal of Mass Spectrometry</i> , 2014 , 360, 54-57	1.9	7
92	Using ellipsometry for the evaluation of surface damage and sputtering yield in organic films with irradiation of argon cluster ion beams. <i>Surface and Interface Analysis</i> , 2011 , 43, 84-87	1.5	7
91	Molecular dynamics simulations of large fluorine cluster impact on silicon with supersonic velocity. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2011 , 269, 1582-1585	1.2	7
90	Secondary ion emission from Si bombarded with large Ar cluster ions under UHV conditions. <i>Applied Surface Science</i> , 2008 , 255, 880-882	6.7	7
89	High-intensity Si cluster ion emission from a silicon target bombarded with large Ar cluster ions. <i>Applied Surface Science</i> , 2006 , 252, 6550-6553	6.7	7
88	Ultra Shallow Junction Formation by Cluster Ion Implantation. <i>Materials Research Society Symposia Proceedings</i> , 1998 , 532, 17		7
87	Yields and images of secondary ions from organic materials by different primary Bi ions in time-of-flight secondary ion mass spectrometry. <i>Rapid Communications in Mass Spectrometry</i> , 2016 , 30, 476-82	2.2	6
86	Ambient analysis of liquid materials with Wet-SIMS. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2016 , 371, 189-193	1.2	6

85	Biomaterial imaging with MeV-energy heavy ion beams. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2014 , 332, 326-329	1.2	6
84	Molecular dynamics study of crater formation by core-shell structured cluster impact. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2012 , 282, 29-32	1.2	6
83	Energy effects on the sputtering yield of Si bombarded with gas cluster ion beams 2011 ,		6
82	High-speed processing with Cl ₂ cluster ion beam. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2009 , 267, 1444-1446	1.2	6
81	High Speed Si Etching with ClF ₃ Cluster Injection 2011 ,		6
80	Low-temperature formation of perovskite PbTiO ₃ films by O ₂ cluster ion-assisted deposition. <i>Materials Chemistry and Physics</i> , 1998 , 54, 255-257	4.4	6
79	Low damage smoothing of magnetic materials using off-normal gas cluster ion beam irradiation. <i>Surface and Coatings Technology</i> , 2007 , 201, 8632-8636	4.4	6
78	Reactive etching by ClF ₃ /Ar neutral cluster beam with scanning. <i>Japanese Journal of Applied Physics</i> , 2016 , 55, 06HB01	1.4	5
77	An electrostatic quadrupole doublet focusing system for MeV heavy ions in MeV-SIMS. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2013 , 315, 356-359	1.2	5
76	Depth profiling analysis of damaged arginine films with Ar cluster ion beams. <i>Surface and Interface Analysis</i> , 2012 , 44, 729-731	1.5	5
75	Molecular dynamics study of monomer and dimer emission processes with high energy gas cluster ion impact. <i>Surface and Coatings Technology</i> , 2007 , 201, 8427-8430	4.4	5
74	Surface oxidation of Si assisted by irradiation with large gas cluster ion beam in an oxygen atmosphere. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2007 , 256, 350-353	1.2	5
73	Secondary ion measurements for oxygen cluster ion SIMS. <i>Applied Surface Science</i> , 2006 , 252, 7290-7292.	6.7	5
72	Molecular dynamics study of particle emission by reactive cluster ion impact. <i>Applied Surface Science</i> , 2006 , 252, 6466-6469	6.7	5
71	Low Damage Smoothing of Magnetic Materials using Oblique Irradiation of Gas Cluster Ion Beam. <i>Materials Research Society Symposia Proceedings</i> , 2004 , 843, 551		5
70	Molecular Dynamics Simulations of Cluster Ion Impact on Diamond Surface. <i>Materials Research Society Symposia Proceedings</i> , 2000 , 650, 3401		5
69	Molecular dynamics simulation of fluorine cluster ion impact. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2000 , 164-165, 546-552	1.2	5
68	Recent Progress in Cluster Ion Beam. <i>Journal of Surface Analysis (Online)</i> , 2008 , 14, 196-203	0.1	5

67	Angled etching of Si by ClF ₃ /Ar gas cluster injection. <i>Japanese Journal of Applied Physics</i> , 2017 , 56, 06HB024	4	
66	Molecular cluster emission in sputtering of amino acids by argon gas-cluster ions. <i>International Journal of Mass Spectrometry</i> , 2015 , 383-384, 31-37	1.9	4
65	Ultrafine Particle Removal Using Gas Cluster Ion Beam Technology. <i>IEEE Transactions on Semiconductor Manufacturing</i> , 2013 , 26, 328-334	2.6	4
64	MeV-energy probe SIMS imaging of major components in washed and fractured animal cells. <i>Surface and Interface Analysis</i> , 2011 , 43, 363-366	1.5	4
63	Sputtering yield measurements with size-selected gas cluster ion beams. <i>Materials Research Society Symposia Proceedings</i> , 2009 , 1181, 150		4
62	Evaluation of surface damage on organic materials irradiated with Ar cluster ion beam 2011 ,		4
61	Size Dependence of Bombardment Characteristics Produced by Cluster Ion Beams. <i>Materials Research Society Symposia Proceedings</i> , 1997 , 504, 93		4
60	Non-linear effects in high energy cluster ion implantation 1997 ,		4
59	Carbon Nanotubes from a Divided Catalyst: the Carbon Transmission Method. <i>Applied Physics Express</i> , 2008 , 1, 034002	2.4	4
58	Molecular Dynamics Study of Surface Structure and Sputtering Process by Sequential Fluorine Cluster Impacts. <i>Materials Research Society Symposia Proceedings</i> , 2004 , 843, 571		4
57	Cationization and fragmentation of molecular ions sputtered from polyethylene glycol under gas cluster bombardment: An analysis by MS and MS/MS. <i>International Journal of Mass Spectrometry</i> , 2018 , 430, 149-157	1.9	4
56	Secondary ion emission from leucine and isoleucine under argon gas-cluster ion bombardment. <i>Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics</i> , 2016 , 34, 03H102	1.3	3
55	Molecular dynamics simulation study of damage formation and sputtering with huge fluorine cluster impact on silicon. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2013 , 303, 170-173	1.2	3
54	Molecular dynamics study of the angular dependence of reactive cluster impacts. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2005 , 241, 594-598	1.2	3
53	Size and energy distribution of gas cluster ion beam measured by energy resolved time of flight mass spectroscopy. <i>Surface and Coatings Technology</i> , 2005 , 196, 198-202	4.4	3
52	Characterization of Damage Induced by Cluster Ion Implantation. <i>Materials Research Society Symposia Proceedings</i> , 2001 , 669, 1		3
51	Recent Progress in Cluster Ion Beam Technology. <i>Hyomen Kagaku</i> , 2010 , 31, 564-571		3
50	Molecular dynamics simulations study of nano particle migration by cluster impact. <i>Surface and Coatings Technology</i> , 2016 , 306, 63-68	4.4	3

49	Development of Low-vacuum SIMS instruments with large cluster ion beam. <i>Surface and Interface Analysis</i> , 2016 , 48, 1119-1121	1.5	3
48	Secondary ion mass spectrometry measurements under ambient and humid conditions using MeV ions. <i>Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics</i> , 2020 , 38, 034014 ¹⁻³		2
47	Low Vacuum SIMS Measurements of Higher Alcohols with MeV-energy Heavy Ion Beam. <i>Transactions of the Materials Research Society of Japan</i> , 2014 , 39, 265-268	0.2	2
46	Etching of metallic materials with Cl ₂ gas cluster ion beam. <i>Surface and Coatings Technology</i> , 2011 , 206, 789-791	4.4	2
45	Low-damage milling of an amino acid thin film with cluster ion beam. <i>Journal of Applied Physics</i> , 2011 , 110, 094701	2.5	2
44	Molecular Dynamics Simulation of Fullerene Cluster Ion Impact. <i>Materials Research Society Symposia Proceedings</i> , 1997 , 504, 81		2
43	Gas cluster ion beam processing 1997 ,		2
42	Total sputtering yields of solids under MeV-energy Si ion bombardment. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2005 , 230, 483-488	1.2	2
41	Low Damage Etching of Polymer Materials for Depth Profile Analysis Using Large Ar Cluster Ion Beam. <i>Journal of Surface Analysis (Online)</i> , 2009 , 15, 275-278	0.1	2
40	Highly Accurate Lipid Analysis and Imaging Mass Spectrometry with Cluster SIMS. <i>Hyomen Kagaku</i> , 2014 , 35, 351-355		1
39	Lipid compounds analysis with MeV-SIMS apparatus for biological applications. <i>Surface and Interface Analysis</i> , 2014 , 46, 353-356	1.5	1
38	MD simulation of small boron cluster implantation 2010 ,		1
37	Japan's Contributions to Ion Beam Technologies 2011 ,		1
36	Biomolecular Emission by Swift Heavy Ion Bombardment 2011 ,		1
35	Cluster Ion Implantation - Prospects and Challenges- 2007 ,		1
34	Experimental Study of Cluster Size Effect with Size-selected Cluster Ion Beam System. <i>Materials Research Society Symposia Proceedings</i> , 2003 , 792, 115		1
33	Secondary neutral and ionized particle measurements under MeV-energy ion bombardment. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2005 , 230, 489-494	1.2	1
32	Ar Cluster Ion Bombardment Effects on Semiconductor Surfaces. <i>Materials Research Society Symposia Proceedings</i> , 2000 , 647, 1		1

31	Low Damage Etching and SIMS Depth Profiling with Large Ar Cluster Ions. <i>Transactions of the Materials Research Society of Japan</i> , 2008 , 33, 1043-1046	0.2	1
30	The effects of cluster size on sputtering and surface smoothing of PMMA with gas cluster ion beams. <i>Transactions of the Materials Research Society of Japan</i> , 2011 , 36, 309-312	0.2	1
29	Imaging Mass Spectrometry with Swift Heavy Ions. <i>Journal of the Mass Spectrometry Society of Japan</i> , 2008 , 56, 201-208	0.2	1
28	Recent Progress of SIMS Technique from Novel Primary Beams to Advanced Mass Spectrometers. <i>Vacuum and Surface Science</i> , 2018 , 61, 426-434	0	1
27	MeV-SIMS measurement of lithium-containing electrolyte. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2020 , 479, 229-232	1.2	1
26	Fabrication of a Si lever structure made by double-angled etching with reactive gas cluster injection. <i>Applied Physics Letters</i> , 2017 , 110, 182105	3.4	0
25	Recent Progress in Cluster Beam Technique. <i>Journal of the Japan Society for Precision Engineering</i> , 2016 , 82, 309-314	0.1	0
24	A Processing Technique for Cell Surfaces Using Gas Cluster Ions for Imaging Mass Spectrometry. <i>Journal of the Mass Spectrometry Society of Japan</i> , 2009 , 57, 117-121	0.2	0
23	Sputtering Properties of Si by Size-Selected Ar Gas Cluster Ion Beam. <i>Transactions of the Materials Research Society of Japan</i> , 2010 , 35, 789-792	0.2	0
22	Optimized Alkali-Metal Cationization in Secondary Ion Mass Spectrometry of Polyethylene Glycol Oligomers with up to / 10000: Dependence on Cation Species and Concentration. <i>Analytical Chemistry</i> , 2020 , 92, 1511-1517	7.8	0
21	Recent Developments of Cluster Ion Beam —From Nano-fabrication to Analysis of Bio-materials—. <i>Journal of the Vacuum Society of Japan</i> , 2016 , 59, 113-120		
20	Quantitative analysis of lipids with argon gas cluster ion beam secondary ion mass spectrometry. <i>Surface and Interface Analysis</i> , 2014 , 46, 1129-1132	1.5	
19	Building and Development of Research Data Management Training Tool. <i>Journal of the Japan Society of Information and Knowledge</i> , 2017 , 27, 362-365	0.1	
18	Processing Techniques of Biomaterials Using Ar Cluster Ion Beam for Imaging Mass Spectrometry. <i>Transactions of the Materials Research Society of Japan</i> , 2010 , 35, 793-796	0.2	
17	Fast Neutral Ar Penetration during Gas Cluster Ion Beam Irradiation into Magnetic Thin Films. <i>Materials Research Society Symposia Proceedings</i> , 2003 , 792, 609		
16	Molecular Dynamics Study Of Surface Morphological Evolution By Cluster Impacts. <i>Materials Research Society Symposia Proceedings</i> , 2003 , 792, 383		
15	EXPRIMENTAL STUDY OF CLUSTER SIZE EFFECT WITH SIZE-SELECTED CLUSTER ION BEAM 2005 , 219-222		
14	Molecular Dynamics Simulations of the Cluster-size Effect on Sputtering Process with Reactive Gas Cluster Ions. <i>Materials Research Society Symposia Proceedings</i> , 2005 , 908, 1		

- 13 Threshold Energy for Generating Damage with Cluster Ion Irradiation. *Materials Research Society Symposia Proceedings*, **2002**, 749, 1
- 12 Study of Surface Morphological Evolution by Cluster Ion Irradiation on Solid Targets. *Materials Research Society Symposia Proceedings*, **2002**, 749, 1
- 11 Secondary Ion Mass Spectrometry with Gas Cluster Ion Beams. *Materials Research Society Symposia Proceedings*, **2000**, 647, 1
- 10 Photoluminescence study of defects induced by B¹⁰H¹⁴ ions. *Materials Research Society Symposia Proceedings*, **2001**, 669, 1
- 9 Computer Simulation of Annealing after Cluster Ion Implantation. *Materials Research Society Symposia Proceedings*, **1998**, 532, 147
- 8 Innovative Technologies in Advanced SIMS Toward Organic and Biological Material Analysis. *Vacuum and Surface Science*, **2021**, 64, 458-465 ○
- 7 SURFACE STRUCTURE DEPENDENCE OF IMPACT PROCESSES OF GAS CLUSTER IONS **2005**, 231-234
- 6 GAS CLUSTER ION BEAM SOURCE FOR SECONDARY ION EMISSION MEASUREMENTS **2005**, 227-230
- 5 High-Speed Nanoprocessing with Cluster Ion Beams. *Transactions of the Materials Research Society of Japan*, **2008**, 33, 1019-1022 ○.2
- 4 A New Sputter Etching Technology by Gas-Cluster Ion Beam.. *Hyomen Kagaku*, **1997**, 18, 743-751
- 3 Vacuum Nanotechnology. Synthesis of New Materials and Characterization of Surfaces and Interfaces. Cluster Ion Implantation and Device Processes.. *Shinku/Journal of the Vacuum Society of Japan*, **1998**, 41, 932-939
- 2 SIMS Depth Profiling of Organic Materials with Ar Cluster Ion Beam. *Transactions of the Materials Research Society of Japan*, **2010**, 35, 785-788 ○.2
- 1 Evaluation of damage depth on arginine films with molecular depth profiling by Ar cluster ion beam. *Transactions of the Materials Research Society of Japan*, **2011**, 36, 313-316 ○.2